

MOEMS IR-technologies and components

Dr. Martin Schädel



Key figures

Non-profit research & development with over 25 years **Competence in Silicon**

2015: turn over 15 Mio €

50% public funding

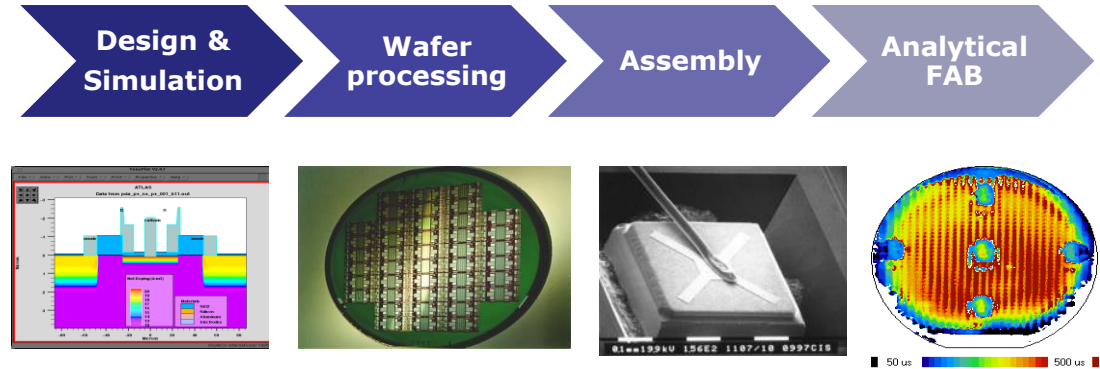
50% industrial research and production

120 employees

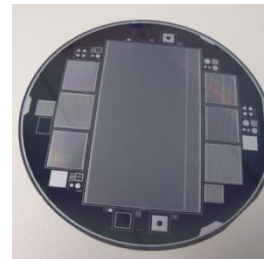
>2000 m² clean room facilities



Technological skills



Business Units



Silicon detectors

Photodiodes,
Radiation +
Particle Detectors



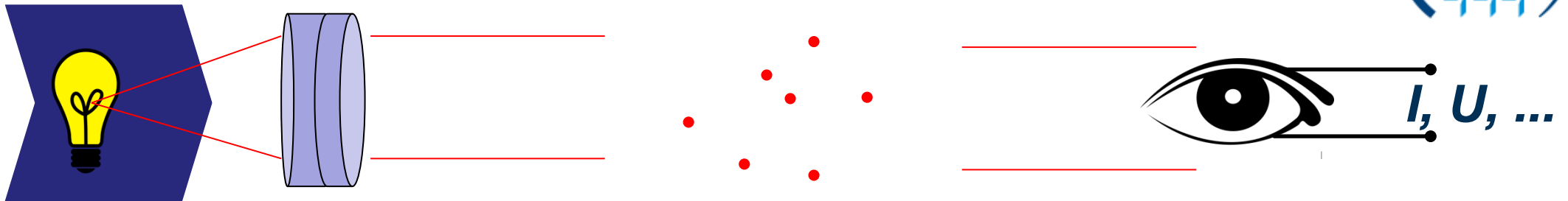
AMOS

Micro optic components
Inclination sensors
Life science components



MEMS

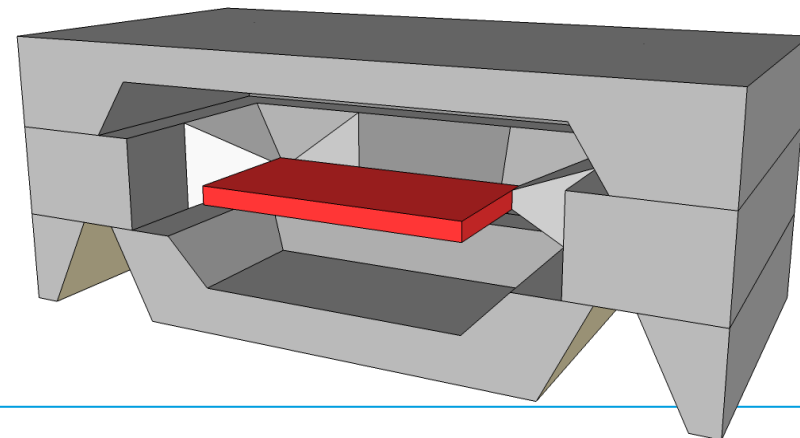
Micro force sensing
Pressure +
Humidity sensors

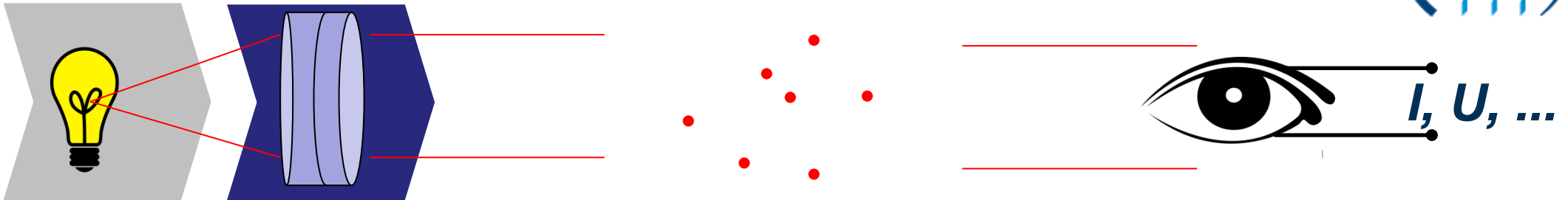


Customer specific MEMS – IR – Sources

Ongoing projects on:

- CMOS processes
- semiconductor and metallic heating elements
- hermetic housing on wafer level

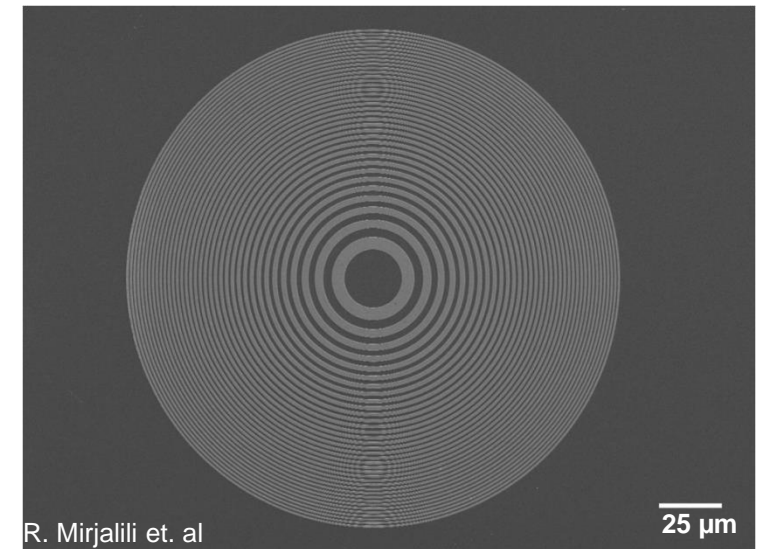


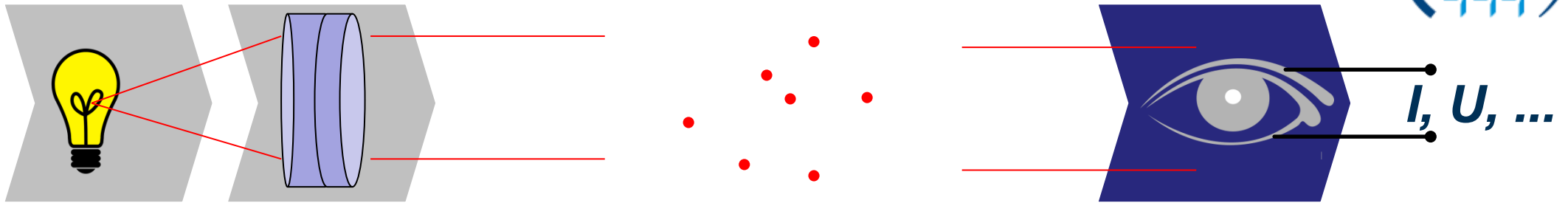


Diffractive silicon optics (DOE) for IR

Ongoing projects on:

- design and manufacturing of zone plates
- system integration
- wafer level packaging

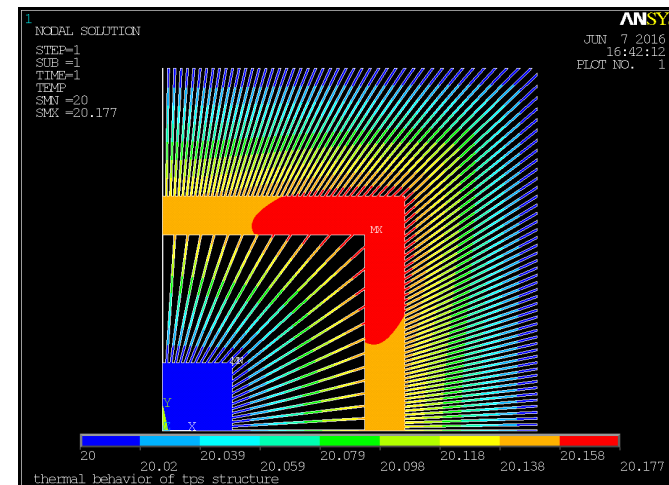
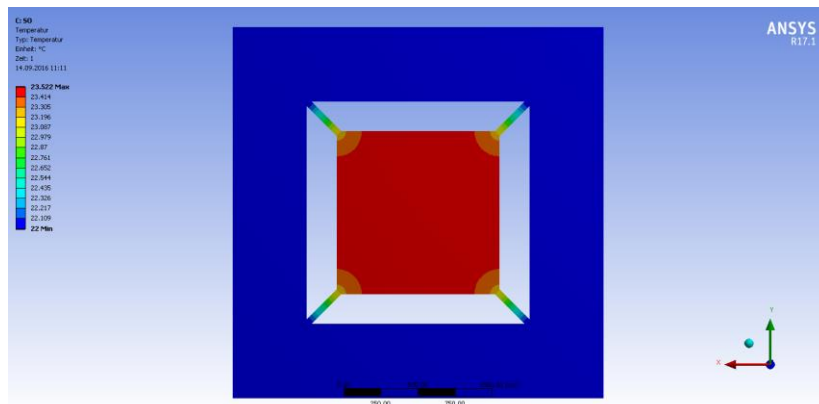


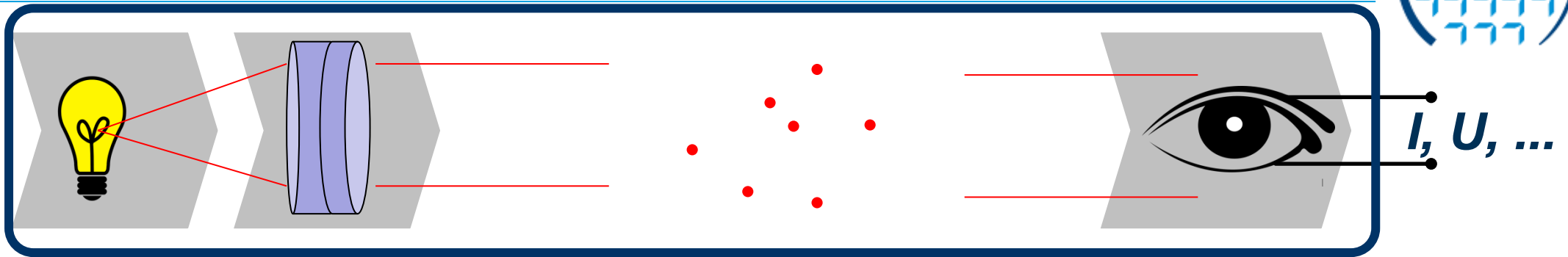


Customer specific IR detectors (Thermopiles and bolometers)

Ongoing projects on:

- Si thermistors and diodes with integrated measuring bridge
- *pn*-Si thermopiles

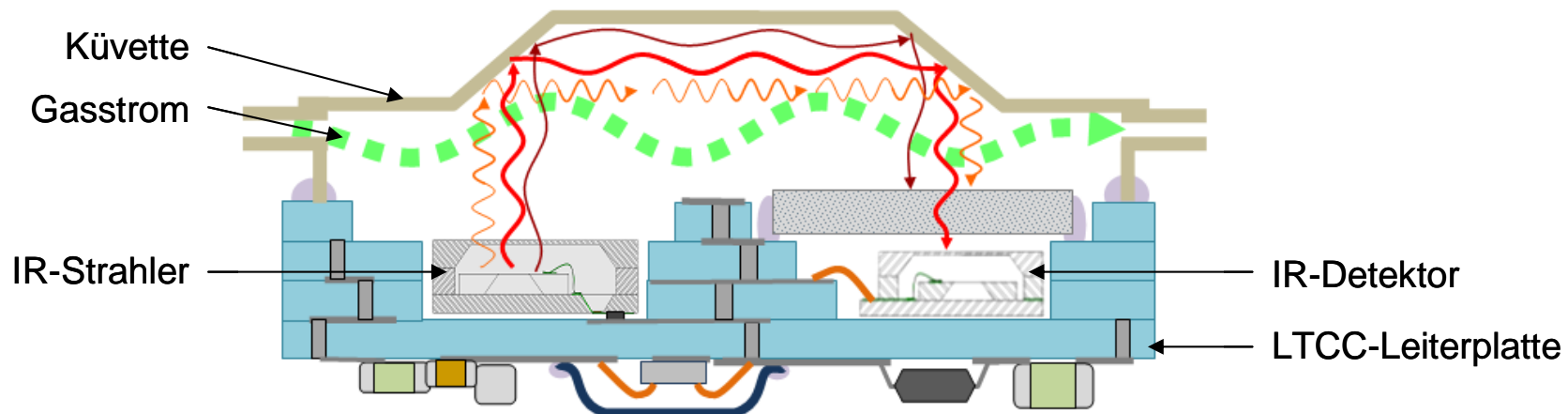




System integration

Ongoing projects on:

- integrated gas sensors



**We are always looking for partners for upcoming
research or industrial projects!**

CiS Forschungsinstitut für Mikrosensorik GmbH

Konrad-Zuse-Straße 14

99099 Erfurt

Germany

www.cismst.de

Dr. Olaf Brodersen

obrodersen@cismst.de

phone: +49361 663 1428

